

INTERFERENCE SEARCH

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L34	44	(plasma rie merie ald cvd deposit\$4 etch\$4 sp?tter\$4).clm. and ((hold\$4 support\$4 susceptor carrier carry\$4 chuck\$4 esc base) near10 (electrode anode cathode)).clm. and ((leaf spring\$4 arc\$3 arch\$4 brush\$4 flap\$4 wing\$4) near5 (metal\$4 conduct\$4)).clm.	US-PGPUB	OR	ON	2006/08/03 13:15

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	263	(akira near2 shimizu yuhsuke near2 fukuoka yasushi near2 fujioka katsushi near2 kishimoto katsuhiko near2 nomoto).in.	US-PGPUB; USPAT	OR	ON	2006/08/03 11:38
L4	5	L3 and plasma.clm. and (electrode anode cathode).clm. and (conduct\$3 metal\$3).clm. and (mesh grid member sheet plate layer shield mask component element strip).clm. and (hold\$3 susceptor carrier chuck esc).clm.	US-PGPUB; USPAT	OR	ON	2006/08/03 11:39
L3	11810	(sharp adj kabushiki adj kaisha).as.	US-PGPUB; USPAT	OR	ON	2006/08/03 11:39
L2	2	L1 and plasma.clm. and (electrode anode cathode).clm. and (conduct\$3 metal\$3).clm. and (mesh grid member sheet plate layer shield mask component element strip).clm. and (hold\$3 susceptor carrier chuck esc).clm.	US-PGPUB; USPAT	OR	ON	2006/08/03 11:39
L5	524	(156/345.51).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/03 11:41
L7	2780	(118/728).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/03 11:52
L6	625	((156/345.43) or (156/345.47)).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/03 11:52
L9	1551	(118/723e).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/03 12:03

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L8	77	7 and (hold\$4 support\$4 susceptor carrier carry\$4 chuck\$4 esc base) same (electrode anode cathode) same (leaf spring\$4 arc\$3 arch\$4 brush\$4 flap\$4 wing\$4)	US-PGPUB; USPAT; USOCR	OR	ON	2006/08/03 12:03
L10	105	9 and (hold\$4 support\$4 susceptor carrier carry\$4 chuck\$4 esc base) same (electrode anode cathode) same (leaf spring\$4 arc\$3 arch\$4 brush\$4 flap\$4 wing\$4)	US-PGPUB; USPAT; USOCR	OR	ON	2006/08/03 12:04
L14	87	10 not 8	US-PGPUB; USPAT; USOCR	OR	ON	2006/08/03 12:07
L15	842482	((156/345.\$) or (315/111.\$)). CCLS. or ("118") or ("427") or ("438") or ("216") or ("204") or ("269") or ("414") or ("279") or ("361")).CLAS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/03 12:08
L18	587	17 and 15	US-PGPUB; USPAT; USOCR	OR	ON	2006/08/03 12:40
L19	557	18 not 8 not 10	US-PGPUB; USPAT; USOCR	OR	ON	2006/08/03 12:41
L20	550	19 not 5 not 6	US-PGPUB; USPAT; USOCR	OR	ON	2006/08/03 12:42
L25	494	plasma and (electrode anode cathode) near5 (contact\$4 press\$4 between interpos\$4) near5 (conduct\$3 metal)	JPO	OR	ON	2006/08/03 12:48
L24	300	L23 not L21 not L22	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/03 12:48
L23	300	(electrode anode cathode) near10 (electrical\$3) near10 (contact\$3) near10 (holder susceptor carrier esc chuck)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/03 12:48
L22	183	plasma and (electrode anode cathode) near5 (member element component sheet plate mesh) near5 (contact\$4 press\$4 between) near5 (conduct\$3 metal)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/03 12:48

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L21	137	plasma and (electrode anode cathode) near5 (leaf arc brush) near5 (contact\$4 press\$4 between) near5 (conduct\$3 metal)	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/03 12:48
L27	303	26 not 24 not 25	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/03 12:50
L17	1628	(plasma rie merie ald cvd deposit\$4 etch\$4 sp?tter\$4).ti,ab, clm. and (hold\$4 support\$4 susceptor carrier carry\$4 chuck\$4 esc base) same (electrode anode cathode) same ((leaf spring\$4 arc\$3 arch\$4 brush\$4 flap\$4 wing\$4) with (metal\$4 conduct\$4))	US-PGPUB; USPAT; USOCR	OR	ON	2006/08/03 12:50
L29	1283	(118/718).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/03 13:10
L30	34	29 and ((leaf spring\$4 arc\$3 arch\$4 brush\$4 flap\$4 wing\$4) near5 (metal\$4 conduct\$4))	US-PGPUB; USPAT; USOCR	OR	ON	2006/08/03 13:11
L26	328	(plasma rie merie ald cvd deposit\$4 etch\$4 sp?tter\$4) and (hold\$4 support\$4 susceptor carrier carry\$4 chuck\$4 esc base) near10 (electrode anode cathode) and ((leaf spring\$4 arc\$3 arch\$4 brush\$4 flap\$4 wing\$4) near5 (metal\$4 conduct\$4))	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/03 13:12